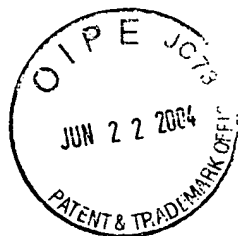


Ifw



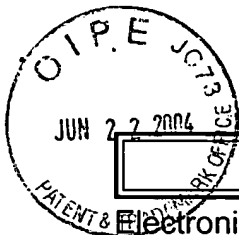
Electronic Filing System (EFS) Data
Electronic Patent Application Submission
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EFS ID: 63071
Application ID: 10680783
Title of Invention: HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER
First Named Inventor: William Jones
Domestic/Foreign Application: Domestic Application
Filing Date: 2003-10-06
Effective Receipt Date: 2004-06-22
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Attorney Docket Number: NONE




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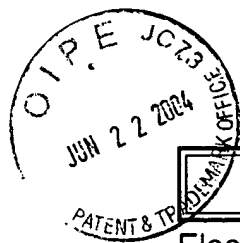
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Title of Invention	HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER									
<p>Application Number: 10/680783 </p> <p>Date: 2003-10-06</p> <p>First Named Applicant: William D.</p> <p>Confirmation Number: 5859</p> <p>Attorney Docket Number:</p>										
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<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Thomas B. Haverstock Registered Number: 32571</td><td>/tbh/</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>SSI04001-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	SSI04001-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
us-ids	SSI04001-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



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Electronic Version v18

Stylesheet Version v18.0

Title of Invention	HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER						
Application Number: 10/680783 .							
Confirmation Number: 5859							
First Named Applicant: William Jones							
Attorney Docket Number:							
Search string: (5186594 or 5769588 or 5906866 or 5975492 or 6122566 or 6355072 or 6454519 or 20030205510 or 20040020518).pn.							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5186594	1993-02-16	Toshima et al.			
	2	5769588	1998-06-23	Toshima et al.			
	3	5906866	1999-05-25	Webb			
	4	5975492	1999-11-02	Brenes			
	5	6122566	2000-09-19	Nguyen et al.			
	6	6355072	2002-03-12	Racette et al.	B1		
	7	6454519	2002-09-24	Toshima et al.	B1		
US Published Applications							
Note: Applicant is not required to submit a paper copy of cited US Published Applications							
init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20030205510	2003-11-06	Jackson	A1		
	2	20040020518	2004-05-02	DeYoung et al.	A1		
Signature							
Examiner Name				Date			

